



Etch, Master, Kukhan Yoon
Process Development Team
Semiconductor R&D Center
Samsung Electronics, Korea



Kukhan Yoon is a master (VP of Technology) of Etch process at Samsung Electronics and leads the memory device (DRAM & VNAND) etching process development in R&D center. He received BS and MS degrees in material science engineering from Yonsei University and started career as an etch engineer at LG semiconductor in 1996. He joined Samsung in 2003 and has been involved in developing the etch process for the next generation memory devices. His major contributions include the HARC (high aspect ratio contact) etching process and integration design not only for DRAM capacitor but also for channel hole in VNAND. His current research interests mainly focus on developing the technologies to overcome the etching limitations with pitch shrinkage.